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TOWNSEND and TOWNSEND and	CREW LLP
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In re application of: Karl Littau et al.	FEB 2 0 2001
Application No.: 08/893,917	
Filed: July 11, 1997	A GADEMVON C
Group Art Unit: 1763	- Weller
For: REMOTE PLASMA CLEANING SOURCE HAVING REDUCED REACTIVITY WITH A SUBSTRATE	

PROCESSING CHAMBER

THE ASSISTANT COMMISSIONER FOR PATENTS Washington, D.C. 20231

Sir:

Transmitted herewith for filing in the above-identified application.

Appellant's Reply Brief Under 37 C.F.R. 1.192 in triplicate

[X} Petition for Extension of Time

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PA 3126642 v1

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February 15, 2001

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